



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Bernd SZYSZKA et al.

Group Art Unit: 1753

Appln. No. : 10/583,124

Examiner: Rodney G. MCDONALD

I.A. Filed : November 29, 2004

Confirmation No.: 1797

For : METHOD AND DEVICE FOR MAGNETRON SPUTTERING

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop _____
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

In accordance with the duty of disclosure under 37 C.F.R. §1.56, and pursuant to the provisions of 37 C.F.R. §§1.97 and 1.98, Applicant brings the following documents to the attention of the Examiner in charge of the above-noted application. The following documents are cited in the International Search Report of International Application PCT/DE2004/013532, of which the instant application is a national stage entry under 35 U.S.C. §371. Moreover, a copy of the International Search Report was previously submitted in the instant application on June 16, 2006.

(1) EP 0 291 044 A, published November 17, 1988. The Examiner cited this as an "X" category document with respect to claims 1-18 of the international application. Moreover, for the Examiner's convenience, Applicant notes U.S. Pat. No. 4,866,032, issued September 12, 1989, in the name of Fujimori et al., which is identified by the Annex to the Search Report as a U.S. patent family member of EP 0 291 044 A;

(2) DE 44 18 906 A1, published December 7, 1995. The Examiner cited this as an “X” category document with respect to claims 1, 2, and 4-18 of the international application. Moreover, for the Examiner’s convenience, Applicant notes U.S. Pat. No. 5,558,750, issued September 24, 1996, in the name of Szczyrkowski, which is identified by the Annex to the Search Report as a U.S. patent family member of DE 44 18 906 A1;

(3) EP 0 537 011 A, published April 14, 1993. The Examiner cited this as an “A” category document with respect to the international application. Moreover, for the Examiner’s convenience, Applicant notes U.S. Pat. No. 5,384,021, issued January 24, 1995, in the name of Thwaites, which is identified by the Annex to the Search Report as a U.S. patent family member of EP 0 537 011 A;

(4) Baranov et al., “In Situ X-Ray Reflectivity For Thin-Film Deposition Monitoring and Control,” Solid State Technology, vol. 42, no. 5, May 5, 1999, pages 53, 55-56, and 58. The Examiner cited this as an “A” category document with respect to the international application.

(5) Vergohl et al., “Real Time Control of Reactive Magnetron-Sputter Deposited Optical Filters By In Situ Spectroscopic Ellipsometry,” Thin Solid Films, vol. 377-378, December 1, 2000, pages 43-47. The Examiner cited this as an “A” category document with respect to the international application.

(6) Vergohl et al., “In Situ Monitoring of Optical Coatings on Architectural Glass and Comparison of the Accuracy of the Layer Thickness Attainable with Ellipsometry and Photometry,” Thin Solid Films, vol. 392, no. 2, July 30, 2001, pages 258-264. The Examiner cited this as an “A” category document with respect to the international application.

Applicant also brings the following documents, discussed in the original disclosure and identified herein by the paragraph number provided in the concurrently submitted substitute specification, to the attention of the Examiner in charge of the above-noted application:

- (7) EP 1 232 293 B1, published August 21, 2002. This document is discussed in paragraph [0004] of the substitute specification.
- (8) EP 0 795 623 A1, published September 17, 1997. This document is discussed in paragraph [0005] of the substitute specification.
- (9) J. Affinito et al., J. Vac. Sci. Technol. A 2 (1984), p. 1275-1284. This document is discussed in paragraph [0005] of the substitute specification.
- (10) J. Strümpfel, *Prozessstabilisierung beim reaktiven Hochratenzerstäuben mittels optischer Emissionsspektroskopie zur industriellen Herstellung von Indium-Zinn-Oxidschichten und Titandioxidschichten*, Chemnitz 1991. This document is discussed in paragraph [0005] of the substitute specification.
- (11) S. Berg, J. Vac. Sci. Technol. A 10 (1992), p. 1592-1596. This document is discussed in paragraph [0021] of the substitute specification.

Each of the above-cited documents are listed on the enclosed completed copy of the PTO-1449 Form. Accordingly, the Examiner is requested to consider these documents and to indicate such consideration by returning a signed and initialed copy of the PTO-1449 Form with the first official communication.

Moreover, copies of the cited non-U.S. patent documents are being submitted herewith. However, pursuant to the U.S. Patent and Trademark Office's decision to waive the requirement under 37 C.F.R. 1.98 (a)(2)(i), copies of the cited/listed U.S. patents and U.S. published patent

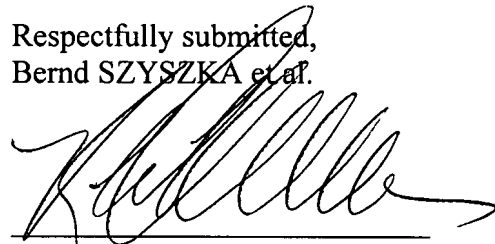
applications are not enclosed herewith. Moreover, if any copies are needed, the Examiner is respectfully requested to contact the undersigned.

Applicant notes that while this Supplemental Information Disclosure Statement is being filed more than three months from the filing date, Applicant has not received a first action on the merits from the U.S. Patent and Trademark Office. Accordingly, consideration of the enclosed document is required under 37 C.F.R. 1.97(b)(3).

However, if the first action on the merit has been mailed prior to the filing date of this Supplemental Information Disclosure Statement, Applicant hereby authorizes the Commissioner to charge any fees necessary to ensure consideration of the documents cited herein to Deposit Account No. 19-0089.

Should there be any questions or comments, the Examiner is invited to contact the undersigned at the below-listed telephone number.

Respectfully submitted,
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